

Session Title:	[TF3] Analysis IV
Session Date:	November 15 (Tue.), 2022
Session Time:	14:30-16:20
Session Room:	Room F (Sicily Room, 1F)
Session Chair:	Dr. Jaehyuck Choi (KRISS, Korea)

[TF3-1] [Invited] 14:30-15:00

Recent Progress in Nanofabrications of T-Gates for InP-HEMTs by Electron Beam Lithography at Fudan University

Yifang Chen (Fudan Univ., China)

[TF3-2] 15:00-15:20

Multi-Functional Semiconductor Nanolasers and Their Applications

Jae-Hyuck Choi and Hagyong Kihm (KRISS, Korea)

[TF3-3] 15:20-15:40

Determination of Wafer Edge Roundness and Its Dependence on Process Factors

Seob Shim, Sungwoo Jung, Jungwon Shin, Kwangsalk Kim, and Kyuhyung Lee (SK siltron, Korea)

[TF3-4] 15:40-16:00

Zero-Kerf Laser Wafer(SiC, GaN, TSV, Sapphire) Dicing Technology by COOL Cut

Seak-Joon Lee (ITI, Korea)

[TF3-5] 16:00-16:20

MoS₂/n-Type GaN Heterojunction and Self-Powered Photodetection with Broad Spectral Response in Ultraviolet-Visible-Near-Infrared Range

V. Janardhanam, I. Jyothi, Hyeon Cheol, M. Zummukhorol, and Chel-Jong Choi (Jeonbuk Nat'l Univ., Korea)